

Indian Nanoelectronics Users' Programme - Idea to Innovation (INUP-i2i)
10th Hands-on Training on “Vacuum Technology and Thin Film Deposition”
Indian Institute of Technology Delhi

26th – 27th September 2025

Workshop Coordinators:

Prof. Neeraj Khare, Prof. Prashant Mishra & Prof. Sujeet Chaudhary



Time (in Hours)	Session- Day 1 (26 th September 2025, Friday)	Venue
09:00 – 09:30	Registration	Room No. 414, Physics Department Library
09:30 – 10:00	Welcome Address and Introduction to INUP-i2i & Hands-on Training Program Prof. Neeraj Khare & Prof. Prashant Mishra	Room No. 414, Physics Department Library
10:00 – 11:00	Lecture: Vacuum Processing of Thin Film for Optoelectronics Application Prof. H.M. Upadhyaya (London South Bank University, UK)	Room No. 414, Physics Department Library
11:00 – 12:00	Lecture: Clean-Room Safety Prof. Bhaskar Mitra (Department of Electrical Engineering, IITD)	Room No. 414, Physics Department Library
12:00 – 13:00	Lecture: E-beam Deposition/Thermal Evaporation Prof. Neeraj Khare (Department of Physics, IITD)	Room No. 414, Physics Department Library
13:00 – 14:00	Lunch	Room No. 414, Physics Department Library
14:00 – 15:30	Lecture: Vacuum Systems & Gauges Prof. Sujeet Chaudhary (Department of Physics, IITD)	Room No. 414, Physics Department Library
15:30 – 16:00	Lecture: Atomic Layer Deposition (ALD) Prof. Samaresh Das (CARE, IITD)	Room No. 414, Physics Department Library
16:00 – 17:30	Lab Session: Vacuum Systems & Gauges & NRF Visit	Physics Department

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Time (in Hours)	Session- Day 2 (27 th September 2025, Saturday)		Venue
09:30 – 10:30	Lecture: Sputtering Prof. P. K. Muduli (Department of Physics, IITD)		Room No.MS 412, Physics Committee Room
10:30 – 13:00	Lab Session: E-beam Deposition/Thermal Evaporation		NRF, Block-6
13:00 – 14:00	Lunch		
14:00 – 16:00	Lab Session: Sputtering/Atomic Layer Deposition (ALD)		NRF, Block-6
16:00 – 17:00	Concluding remarks		Room No.MS 412, Physics Committee Room